FLAT PANEL DISPLAY (FPD) CONFERENCE 97
Tuesday, February 4, 1997, 3F, KOEX Conference Room
Program Chairman: Choon-Rae Lee, Technology Managing Director, LG Electronics

08:30 - 08:55 Registration

PLENARY SESSION
Co-Chairs: Shin-Doo Lee, SoGang University
Young-Kwon Song, Merck Korea

08:55 - 09:00 Opening Remarks

09:00 - 09:10 Keynote Address
Choon-Rae Lee, Program Chairman, Technology Managing Director / LG Electronics

09:10 - 09:40 PDP, LCD Market Forecast
Hideki Wakabayashi / Nomura Research

09:40 - 10:00 Status Report on U.S. Display Technology and Manufacturing
Samuel Musa / Michigan University

10:00 - 10:10 Break

SESSION I. PDP TECHNOLOGY TREND
Co-chairs: Sung-Ki Kang, Samsung Display Devices
Sung-Sik Pak, Orion Electronics
Myung-Ho Park, LG Electronics

10:10 - 10:30 Drive IC Cost Down Technology
Masayuki Kurozumi / Texas Instruments

10:30 - 10:50 The Basic Technology of Advanced Screen Printing Process
Y. Sano / Micro-Tec Co.

10:50 - 11:10 Newest Process Technology and Equipment for Manufacturing Large Sized PDPs
Yasuyuki Kani / Noritake Ltd.

11:10 - 13:00 Lunch
SESSION II. LCD TECHNOLOGY TREND

Co-chairs: Won-Ki Jang, Samsung Electronics
Dong-Jun Ahn, Hyundai Electronics
Ho Lee, LG Electronics
Ha-Chul Park, Applied Komatsu Technology
Jin Jang, KyungHee University

13:00 - 13:20 Low Temperature Poly-Silicon Technologies
Hoe-Sup Soh / LG Electronics

13:20 - 13:40 Low Temperature Poly-Silicon Technologies
Gongxue Hua / Lambda Physic Japan Co., Ltd.
Shin-Ichi Ishizaka / Japan Steel Works

13:40 - 14:00 A High Throughput Ion Implanter for AMLCD
Kyung Ho Lee / Eaton Corp.

14:00 - 14:20 Wide Viewing Angle Technology
Kyung-Hyun Kim / Samsung Electronics

14:20 - 14:40 4th Generation of Glass Size &
Photolithography and Deposition Equipments
Hidetoshi Mori / Nikon

14:40 - 15:00 CVD, PVD & Dry Etch for Generation 4
John White / Applied Komatsu Technology

15:10 - 15:20 Break

15:20 - 15:40 Sputtering System for Large Scale Flat Panel Display
Masasuke Matsuda / ULVAC Japan

15:40 - 15:00 Plate Design for Testability for Voltage Imaging™ and Its Impact on
Cost of Ownership for In Process FPD Test Systems
Alan Nolet / Photon Dynamics

15:00 - 15:20 PECVD, Sputtering and Dry Etching on Large Area Glass Substrates
Francois Leblanc / Balzers SA

15:20 - 15:40 Photo-alignment Technology in LCDs
Soon-Bum Kwon / LG Electronics